



[10191/3935]

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor(s) : Franz LAERMER et al.
Serial No. : 10/506,457
Filed : January 5, 2005
For : DEVICE AND METHOD FOR ANISOTROPIC PLASMA
ETCHING OF A SUBSTRATE, A SILICONE BODY IN
PARTICULAR
Examiner : Allan Olsen
Art Unit : 1763
Confirmation No. : 9990

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, Virginia 22313-1450 on:

Date: MAY 7 2007

Signature: CLL

AMENDMENT

S I R:

In response to the Office Action of November 13, 2006, kindly amend the above-captioned application without prejudice as follows:

Amendments to the Claims are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks begin on page 7 of this paper.